

Supporting Information

A flexible and fully integrated wearable pressure sensing chip system for multi-scenario applications

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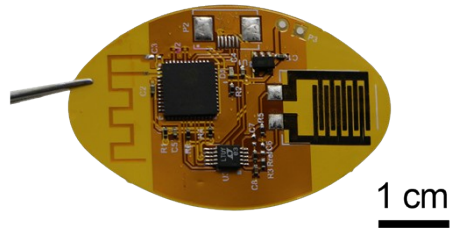
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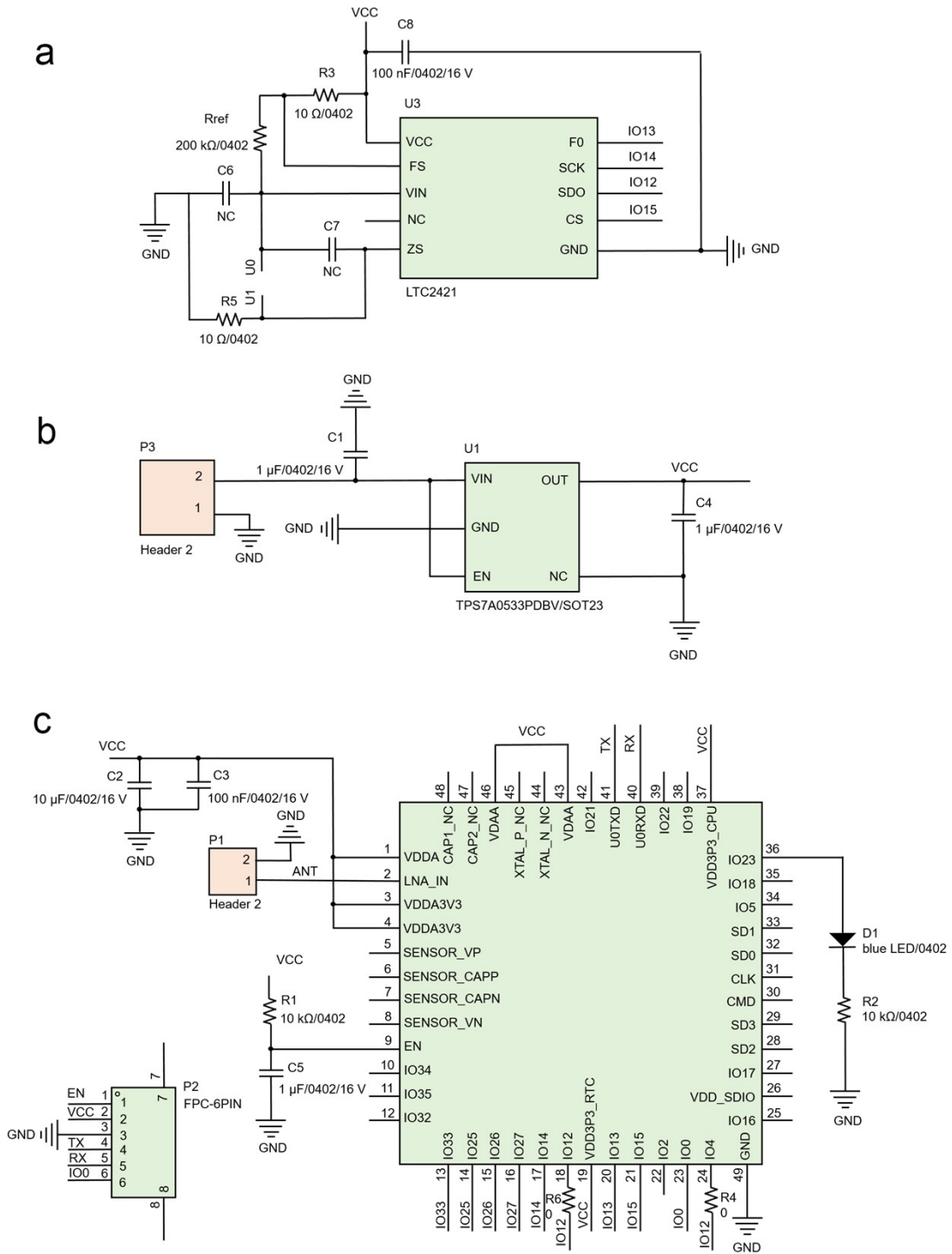
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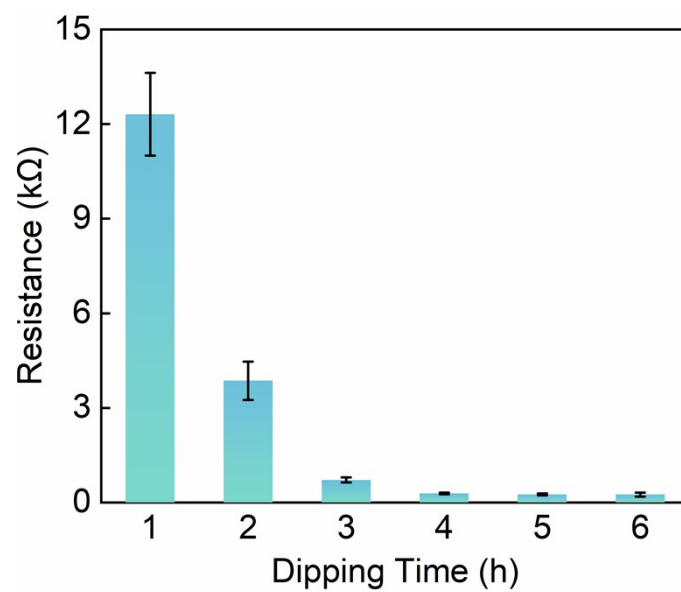
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Figure S1. The FPCB and the interdigitated electrode based on PI film.



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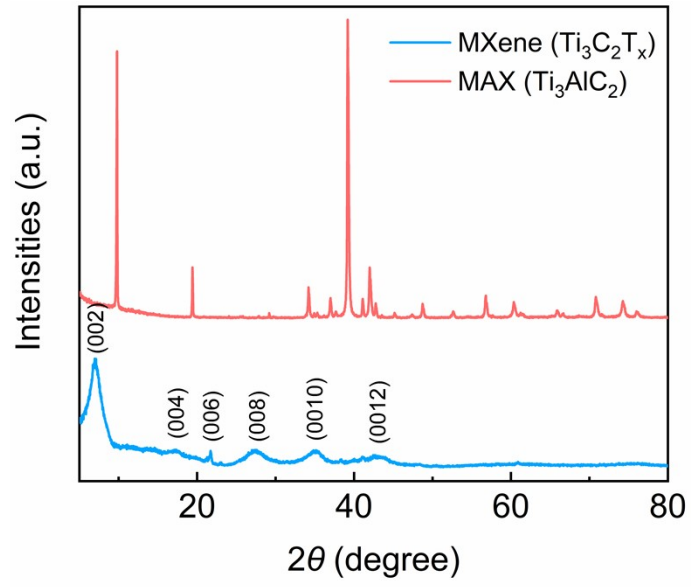
Figure S2. Schematic diagram of the circuit.



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7 **Figure S3.** Resistance of the MX@Sponge under different immersing time in MXene aqueous

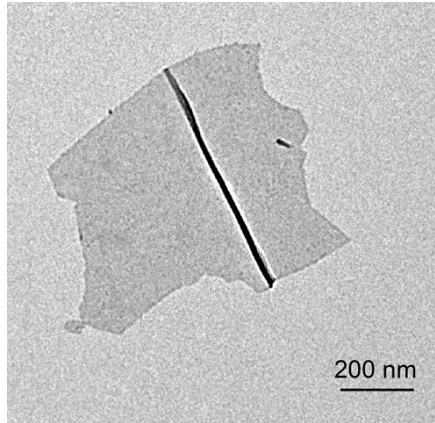
8 solution. The resistance of MX@Sponge becomes stable after 4-hour immersion.



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Figure S4. XRD pattern of MAX powder and MXene nanosheets.

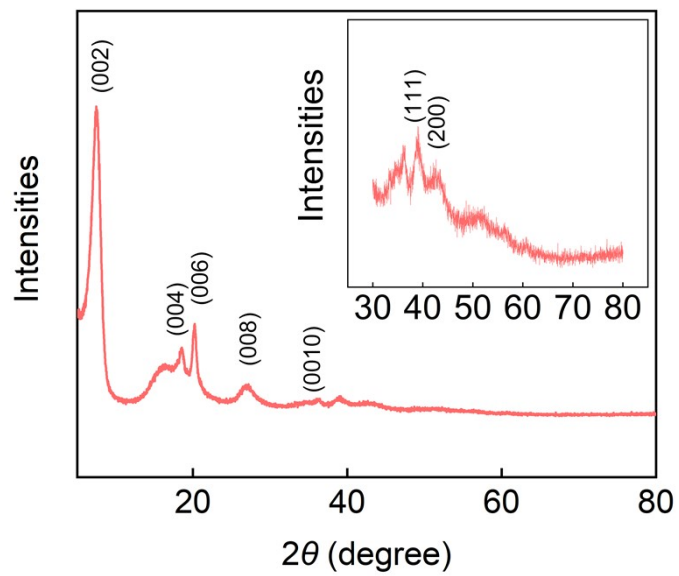


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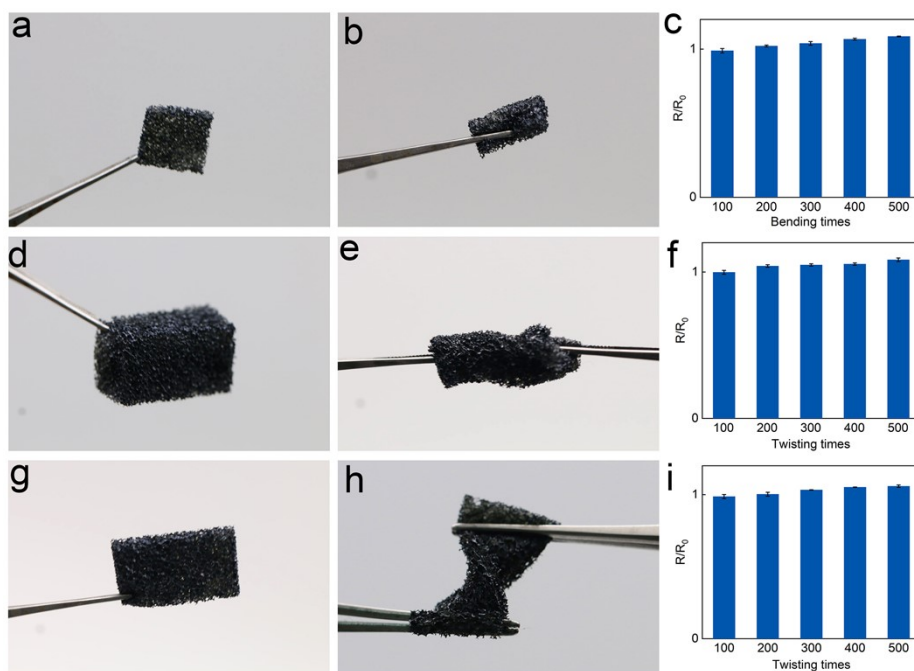
Figure S5. TEM image of MXene nanosheet.



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15 **Figure S6.** XRD pattern of Ag@MX. The peaks at 7.2°, 18.3°, 20°, 26.5°, and 38° indicate the
16 presence of MXene. Peaks at 39° and 42° indicate the formation of AgNPs.

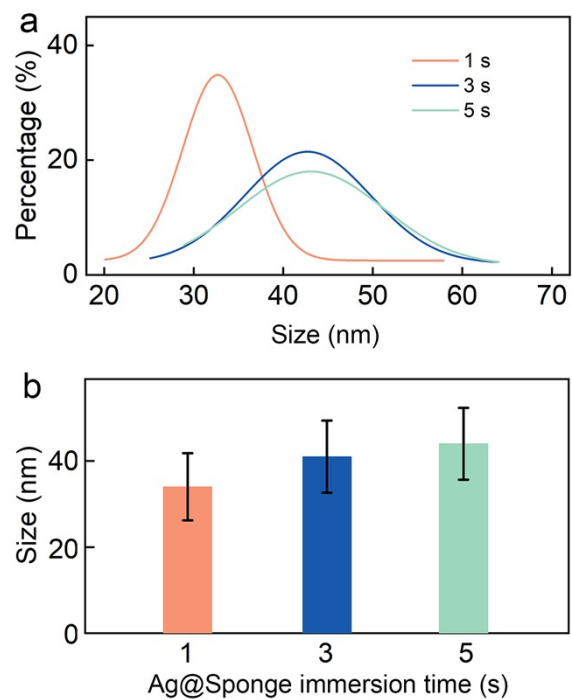
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19 **Figure S7.** The illustration and resistance change of 3-Ag@MX@Sponge under bending and
 20 twisting status. (a, b) Pristine status and bending status of the 3-Ag@MX@Sponge (10 mm × 10
 21 mm × 2 mm), (c) relative resistance of the 3-Ag@MX@Sponge after different times of bending. (d,
 22 e) Pristine status and twisting status of the 3-Ag@MX@Sponge (20 mm × 10 mm × 10 mm), (f)
 23 relative resistance of the 3-Ag@MX@Sponge after different times of twisting. (g, h) Pristine status
 24 and twisting status of the 3-Ag@MX@Sponge (20 mm × 10 mm × 2 mm), (i) relative resistance of
 25 the 3-Ag@MX@Sponge after different times of twisting.

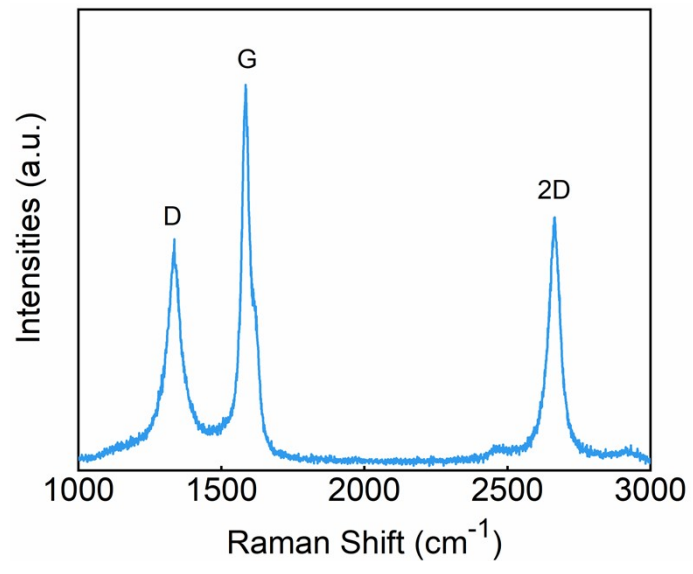
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28 **Figure S8.** The diameter distribution (a) and the average size (b) of AgNPs with different

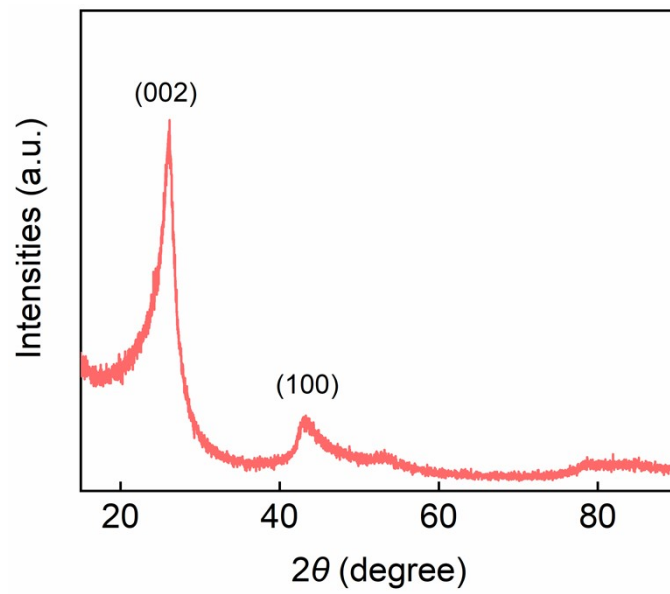
29 immersing time in 1 mmol/L AgNO₃.



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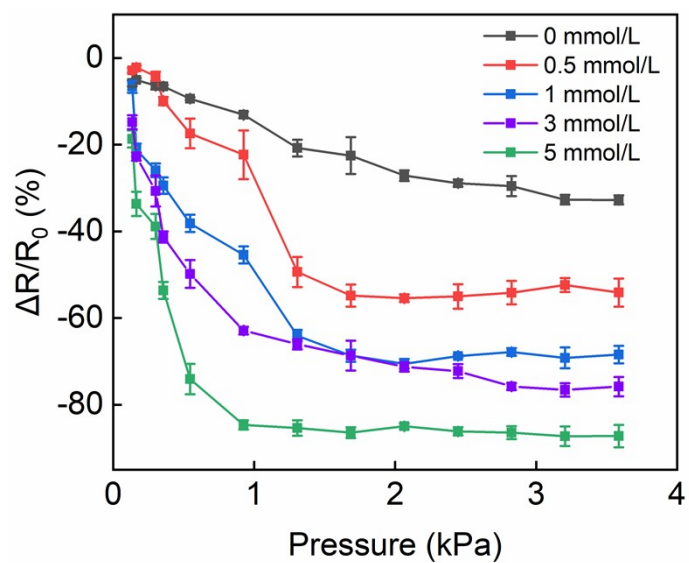
Figure S9. Raman spectra of LIG.



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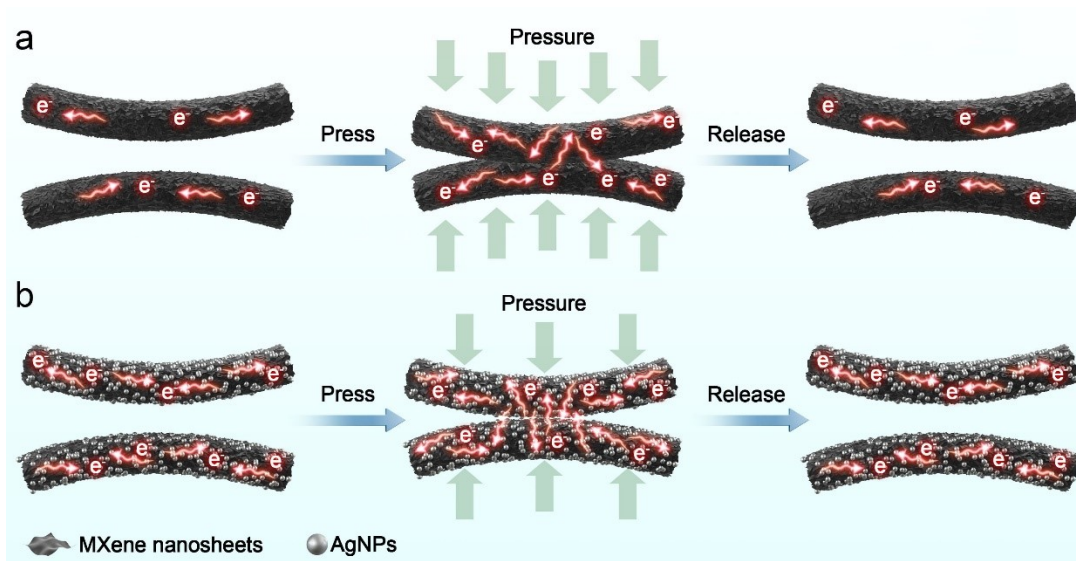
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Figure S10. XRD pattern of LIG.



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35 **Figure S11.** RRC of the sensors to different applied pressure. The sensors were fabricated by
 36 Ag@MX@Sponge with an immersing time of 3 s in 0, 0.5, 1, 3, and 5 mmol/L AgNO₃ solution,
 37 respectively.

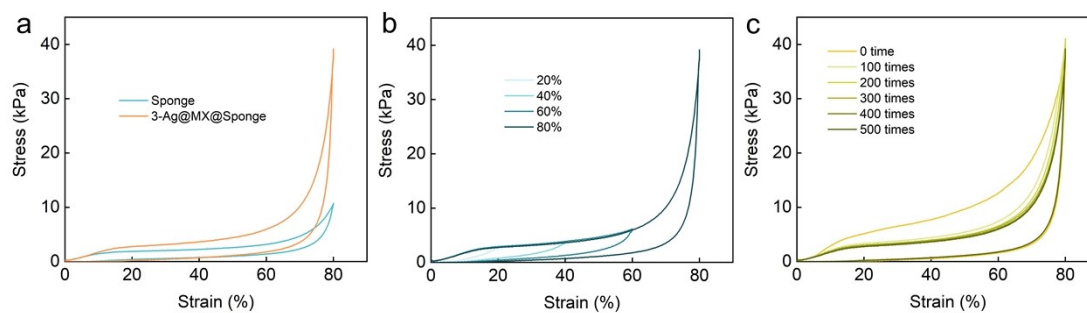


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39 **Figure S12.** Schematic illustration showing the change of the number of conductive paths in the (a)
 40 MX@Sponge and (b) Ag@MX@Sponge with or without external pressure.

41

42 **Note S1.** The sensing mechanisms of MX@Sponge sensor and Ag@MX@Sponge sensor are illustrated
 43 in **Figure S12**. The compressive deformation under external pressure results in the formation of
 44 percolative network—that is, conductive paths are unavailable till the critical threshold of certain volume
 45 fractions of conductive agent is met in MX@Sponge.¹⁻³ Upon further compression, the conductive
 46 network becomes more developed in a given volume of the sponge while more contacts are formed
 47 between the sponge and the LIG-based interdigitated electrode, leading to much decreased sensor
 48 resistance (**Figure S12a**). When the pressure further increases, the number of the conductive paths
 49 becomes saturated, leading to stable resistance of the sensor. Once the pressure is released, the
 50 deformation of the sponge restores and the sensor resistance increases to the original value. The
 51 decoration of AgNPs on the MX@Sponge increases the sensitivity and the maximum RRC of the sensor.
 52 This significant improvement can be attributed to the contact between the AgNPs on the backbones. In
 53 MX@Sponge sensor, the contact between MXene nanosheets contributes to the change of the resistance.
 54 The surface of MX@Sponge becomes “rough” once coated with AgNPs. Therefore, even at a lower
 55 pressure, the AgNPs touch with each other and increase the number of conductive paths, thus leading to
 56 a higher sensitivity compared with the MX@Sponge sensor (**Figure S12b**). By controlling the growing
 57 time of AgNPs, the sensitivity of the Ag@MX@Sponge sensor can be tunable. A higher growing density
 58 of AgNPs correspond to a higher sensitivity of the sensor.



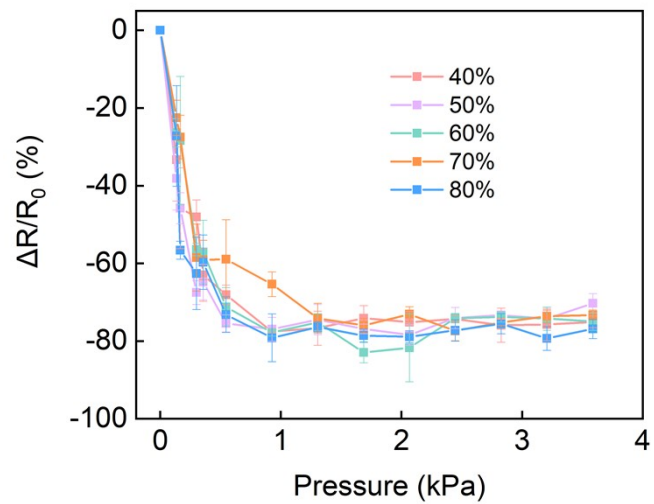
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60 **Figure S13.** (a) The compressive strain-stress curves of Sponge and 3-Ag@MX@Sponge under 80%
 61 compression strain. (b) The compressive strain-stress curves of 3-Ag@MX@Sponge under different
 62 compression strain. (c) The compressive strain-stress curves of 3-Ag@MX@Sponge at 80%
 63 compression strain after being compressed for different times.

64

65 **Note S2.** **Figure S13a** shows the compressive strain-stress curves of Sponge and 3-Ag@MX@Sponge
 66 under 80% compression strain, respectively. The Ag@MX@Sponge perform higher compressive stress
 67 compared with pure sponge. **Figure S13b** indicates the compressive strain-stress curves of 3-
 68 Ag@MX@Sponge under different compression strain. **Figure S13c** shows the compressive strain-stress
 69 curves of 3-Ag@MX@Sponge at 80% compression strain after being compressed for different times.
 70 The compressive stress decreases after the first 100 compressing cycles. While during the following
 71 cycles, the sample shows similar compressive behavior. Such behavior also shows the good repeatability
 72 and durability of our wearable pressure sensor.

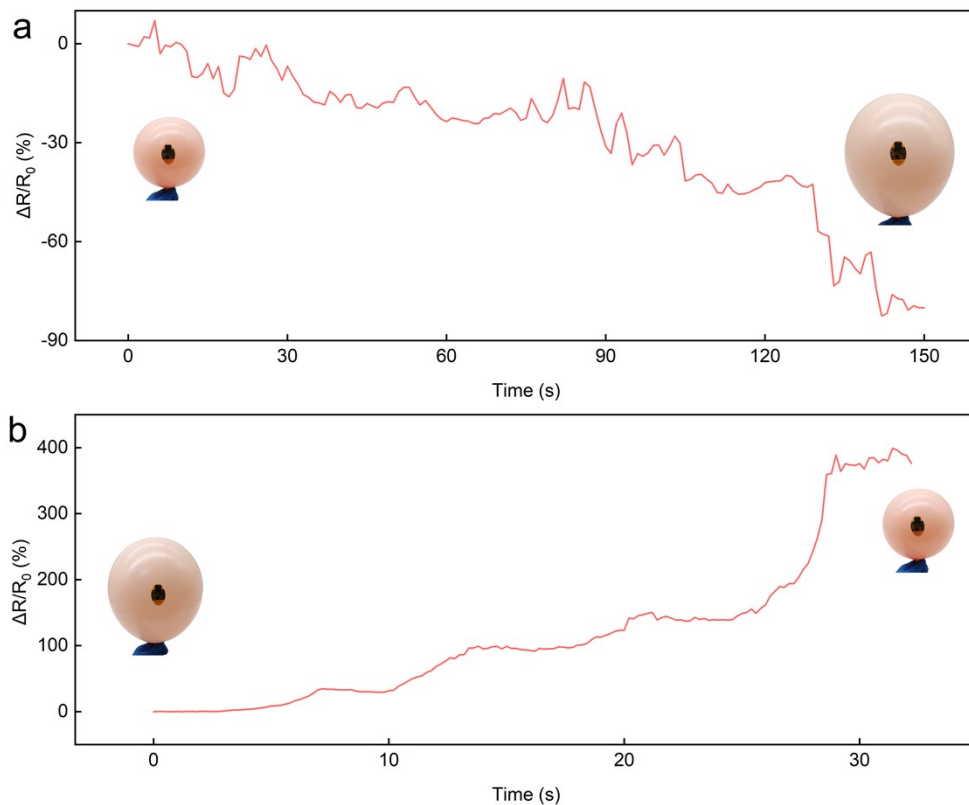
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75 **Figure S14.** RRC of 3-Ag@MX@Sponge sensor to different pressure under various relative humidity.

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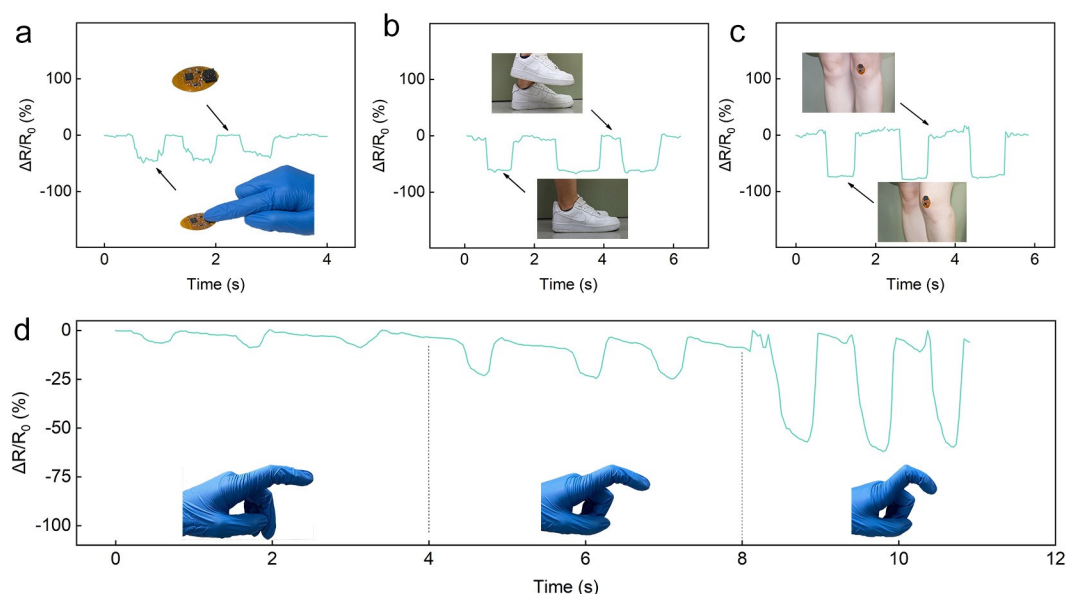


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78 **Figure S15.** RRC of the sensor under inflating (a) and deflating (b) process of the balloon.

79

80 **Note S3.** Inflating process of the balloon is used to simulate the fruit growth. The PI film in this
 81 study is not stretchable and consequently the Ag@MX@Sponge cannot be stretched during inflating
 82 or deflating process, which eliminates the error by external tensing or relaxing. As shown in **Figure**
 83 **S15a**, the RRC shows a decreasing trend during inflating process. This phenomenon is attributed to
 84 the pressure exerted on the conductive sponge during the swelling of the balloon inflation. The RRC
 85 under deflating process of the balloon is demonstrated in **Figure S15b**. The obvious increasing trend
 86 of the resistance is observed, which is opposite to the inflating process. The simulation result
 87 indicates that the sensing chip prepared in this study has the potential to monitor the growth of fruits
 88 and vegetables or other agricultural products.



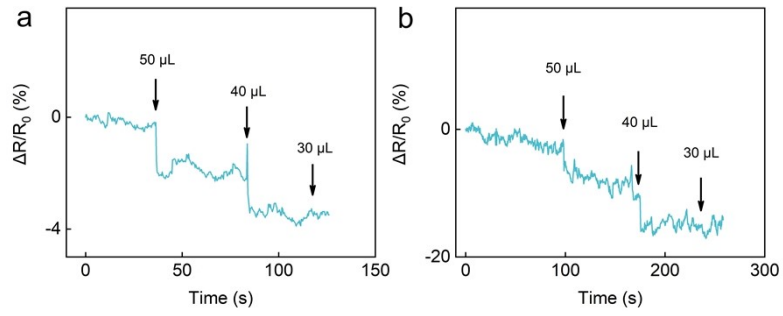
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90 **Figure S16.** RRC of the 1-Ag@MX@Sponge sensor (f) finger pressing-releasing cycles, (g) foot
 91 stepping, (h) knee bending, (i) finger bending.

92

93 **Note S4.** We press the conductive sponge repeatedly with finger and the corresponding output signal
 94 is collected with results demonstrated in **Figure S16a**. The RRC decreases during compression and
 95 the variation is resulted from the uncontrollable finger pressure. Then, the chip is attached to the
 96 shoe sole to monitor the footsteps. As shown in **Figure S16b**, the sensing behavior is similar to
 97 finger pressing and shows good repeatability as well. The maximum RRC is more stable than finger
 98 pressing, which is attributed to the saturation of the conductive paths in conductive sponge under
 99 the pressure generated by foot stepping. Besides, the chip can also be used to monitor knee bending.
 100 As shown in **Figure S16c**, the RRC decreases when the knee is bending. During this process, the
 101 knee exerts pressure on the conductive sponge and the RRC shows an obvious decrease. We also
 102 use the chip to detect the finger bending. As shown in **Figure S16d**, the chip shows different
 103 response under different bending degrees and higher bending degrees result in a higher RRC.

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105

106 **Figure S17.** RRC of the (a) MX@Sponge sensor and (b) 3-Ag@MX@Sponge sensor under the
 107 pressure generated by different amount of water drop.

108

109 **Table S1.** Normalized weight percentage of C, Ti, and Ag in Ag@MX@Sponge with different
110 immersing time of MX@Sponge in 1 mmol/L AgNO₃.

Time/s	Ag/%	C/%	Ti/%
1	0.96	19.18	79.86
3	1.36	17.03	81.61
5	1.63	23.38	74.98

112 **Table S2.** Comparison of the sensitivity and linear detection range of Ag@MX@Sponge sensors
 113 with other reported sponge-based wearable pressure sensors.

Sensors	Sensitivity/kPa ⁻¹	Linear detection range /kPa	Reference
Carbonized melamine sponge sensor	0.36	N/A	4
Carbon black-TPU sponge sensor	1.12	0–60	5
Graphene/AgNWs-coated sea sponge sensor	0.29	0–2.5	6
Reduced graphene oxide- PANI-based sponge sensor	0.77	<6	7
CaCu ₃ Ti ₄ O ₁₂ @PU sponge sensor	0.73 0.135	0–1.6 1.6–22.8	8
MXene@Chitosan@PU sponge sensor	0.014 0.015	<6.5 6.5–85.1	9
Graphene-based sponge sensor	1.04 0.12	0.013–0.26 0.26–20	10
Reduced graphene oxide- based sponge sensor	0.26 0.03	0–2 2–10	11
Reduced graphene oxide@PU sponge sensor	1.06 2.82	<40 40–58	12
MX@Sponge sensor	0.10	0.14–2.83	
1-Ag@MX@Sponge sensor	0.20	0.14–2.47	This
3-Ag@MX@Sponge sensor	0.41	0.14–1.31	work
5-Ag@MX@Sponge sensor	0.90	0.14–0.55	

114 TPU: thermoplastic polyurethane; PU: polyurethane; PANI: polyaniline; N/A: not available.

Table S3. Bill of components.

Components	Description	Footprint	Value and series number
C1, C4, C5	Capacitor	0402	1 μ F
C2	Capacitor	0402	10 μ F
C3, C8	Capacitor	0402	100 nF
D1	High Conductance Fast Diode	0402	Diode 1N4148
P1	Pin for sensor		3.937 mm pitch
P2	FPC/FFC connector		0.5 mm pitch
P3	Pin for power		2.54 mm pitch
R1, R2	Resistor	0402	10 k Ω
R3, R5	Resistor	0402	10 Ω
R4, R6	Resistor	0402	0
R _{ref}	Resistor	0402	200 k Ω
U1	LDO	SOT23-5	TPS7A05
U2	Microcontroller	QFN7X7-48	ESP32-PICO-D4
U3	ADC	MS10	LTC2421

116 FPC: flexible print circuit; FFC: flexible flat cable; LDO: low-dropout regulator; ADC: analog-to-

117 digital converter.

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